

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re New Patent Application of )  
Hidekazu MIYAIRI et al. )  
Japanese Priority Application Nos. )  
2002-268222 & 2002-274220 ) Attn: Applications  
Filed: 09/13/2002 & 09/20/2002 ) Branch  
For: LASER APPARATUS, LASER )  
IRRADIATION METHOD, AND )  
MANUFACTURING METHOD OF )  
SEMICONDUCTOR DEVICE ) Date: September 10, 2003

PRELIMINARY AMENDMENT

Commissioner for Patents  
P.O. Box 1450  
Alexandria, Virginia 22313-1450

Sir:

Please preliminarily amend the subject application as follows: